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IDENTIFIER:  
TITLE: SAMPLE HOLDING DEVICE AND SCANNING-TYPE  
ALIGNER

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ABSTRACT:

PROBLEM TO BE SOLVED: To provide a sample-holding device, in which reticle is difficult to be shifted due to an inertial force at the time of acceleration/deceleration of a stage, and the surface of the sample can be fixed and held so as not to deviate.

SOLUTION: A reticle is fixed and held by a sample-holding device 60 on a reticle stage 4 of a scanning-type scan aligner. The sample-holding device 60 is provided with a clamper 63, pivotally supported so as to be rotatable for interposing the reticle between the sample-holding device

60 and the stage 4. The clamper 63 is provided with pressurizing devices 70a-70c whose pressurizing force is independently adjustable. Each pressurizing device 70a-70c respectively interposes the different parts of the reticle. Even if undulation or projection and recession is present on the reticle, the reticle is precisely held and fixed on the reticle stage 4. A rotary shaft center 62 of the clamper 63 is made substantially coincident with the surface height of the reticle.

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